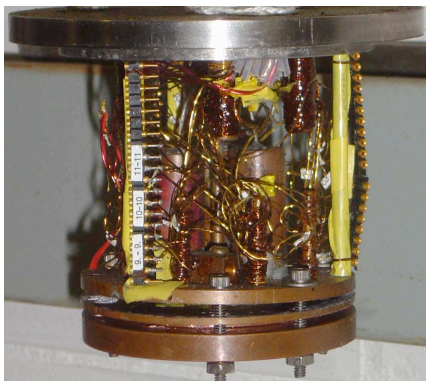
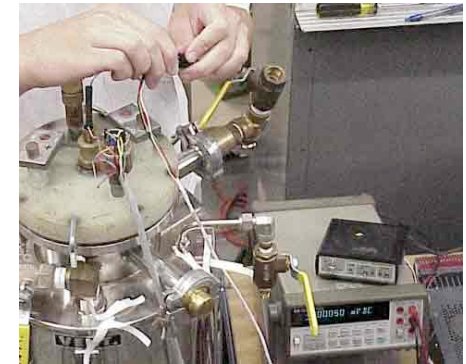


Instrumentation & Measurement Techniques



J.M Pfothauer
University of Wisconsin - Madison



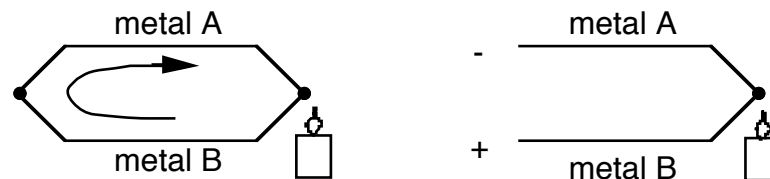
Outline

- Temperature measurement
 - Thermocouples
 - Fundamentals
 - Commercial configurations
 - Thermopiles
 - Resistance thermometers
 - Considerations
 - Options
 - Uncertainties
 - Do's and don'ts
- Pressure measurement
- Flow measurement
- Level measurement



Thermocouples - Fundamentals

- *Seebeck, 1821: Two wires of dissimilar metals joined at both ends display a continuous current if one end is heated. If the circuit is broken, a voltage is established which is a function of the junction temperature and the composition of the metals.*



- *Because temperature measurements via thermocouples are common and deceptively simple, many errors in their use and interpretation are also common. To avoid these, it is helpful to understand the physical principles behind the signal generated by a thermocouple ...*



Thermocouples - Fundamentals

- The electric current, J , associated with the flow of electrons is given by:

$$J = \left(\frac{\tilde{\mu}}{e} - T \right)$$

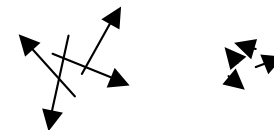
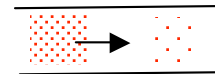
- The thermal current, q , associated with the same flow of electrons is:

$$q = T J k T = \frac{T}{e} \tilde{\mu} \left(T^2 + k \right) T$$

Here

- $\tilde{\mu}$, the Seebeck coefficient, is a measure of the tendency of electric currents to carry heat and for heat currents to induce electrical currents.
 - $\tilde{\mu} = -e \phi$, where e is the electric charge, ϕ the electric potential, and μ is the chemical potential (which is a function of composition and temperature).
 - σ and k are the electric and thermal conductivity respectively
- The net motion of the electrons arises from three different gradients:
 - $\nabla \phi$ (voltage)
 - $\nabla \mu$ (concentration gradient)
 - ∇T (thermal energy gradient)

E_1 — E_2



Thermocouples - Fundamentals

- Consider the circuit as shown connected to a potentiometer: the two 'leads' have the same composition and temperature same chemical potential

$$\mu(l_5) = \mu(l_0) \quad \text{or} \quad \tilde{\mu}(l_5) - \tilde{\mu}(l_0) = e \int_{l_0}^{l_5} \left(\frac{d\mu}{dl} \right) dl$$

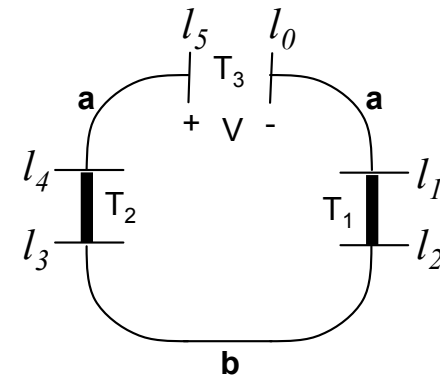
- With zero current flow, $J = 0$, we have for any position along the path from l_0 to l_5 :

$$\tilde{\mu}(l) = \tilde{\mu}(l_0) + e \int_{l_0}^l \left(\frac{d\mu}{dl} \right) dl$$

- Combining the above two equations, we have:

$$\mu(l_5) - \mu(l_0) = e \int_{l_0}^{l_5} \left(\frac{d\mu}{dl} \right) dl$$

- Note that an open circuit voltage arises from regions where $\frac{d\mu}{dl} \neq 0$



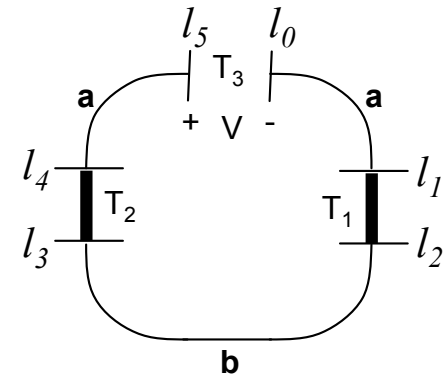
Thermocouples

- Voltage difference between points 0 and 5:

$$(l_5) \quad (l_0) = \int_0^{l_5} (l, T) \frac{dT}{dl} dl$$

- open circuit voltage arises from regions of $dT/dl \neq 0$

$$(l_5) \quad (l_0) = \int_0^{l_1} a(T) \frac{dT}{dl} dl + \int_{l_1}^{l_2} b(T) \frac{dT}{dl} dl + \int_{l_2}^{l_3} a(T) \frac{dT}{dl} dl + \int_{l_3}^{l_4} b(T) \frac{dT}{dl} dl + \int_{l_4}^{l_5} a(T) \frac{dT}{dl} dl$$



Note that

$$\int_{T_3}^{T_1} a(T) dT + \int_{T_2}^{T_3} a(T) dT = \int_{T_1}^{T_2} a(T) dT$$

- Note that although \int_a and \int_b are known, (l, T) in the joint is unknown. Joints must be in regions where $dT/dl = 0$.

Then:

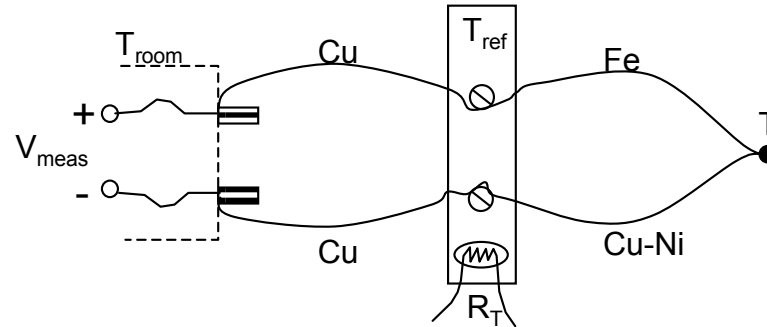
$$(l_5) \quad (l_0) = \int_{T_1}^{T_2} [a(T) - b(T)] dT = \int_{T_1}^{T_2} ab(T) dT$$

- $\int_{T_1}^{T_2} ab(T) dT$ is found in the tables! It represents the difference in the voltage generated by material a and material b, both spanning the temperatures 0°C and T_2 .



Commercial Configurations

- Software compensation:



$$V_{meas} = \int_{T_{room}}^{T_{ref}} \alpha_{Cu} dT + \int_{T_{ref}}^T \alpha_{Fe,C} dT + \int_{T_{ref}}^{T_{room}} \alpha_{Cu} dT = \int_{T_{ref}}^T \alpha_{Fe,C} dT$$

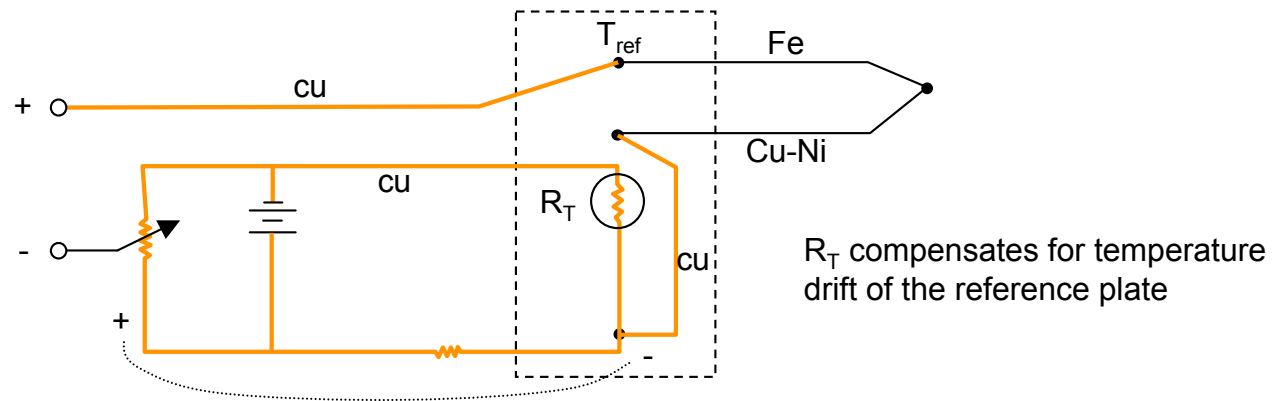
$$\underbrace{\int_{T_{ref}}^T \alpha_{Fe,C} dT}_{V_{meas}} = \underbrace{\int_{T_o}^T \alpha_{Fe,C} dT}_{V(T)} - \underbrace{\int_{T_o}^{T_{ref}} \alpha_{Fe,C} dT}_{V_{ref} \text{ (known)}}$$

- Measure R_T to obtain T_{ref} V_{ref}
- Solve for $V(T)$, use tables to determine T



Commercial Configurations

- Hardware compensation

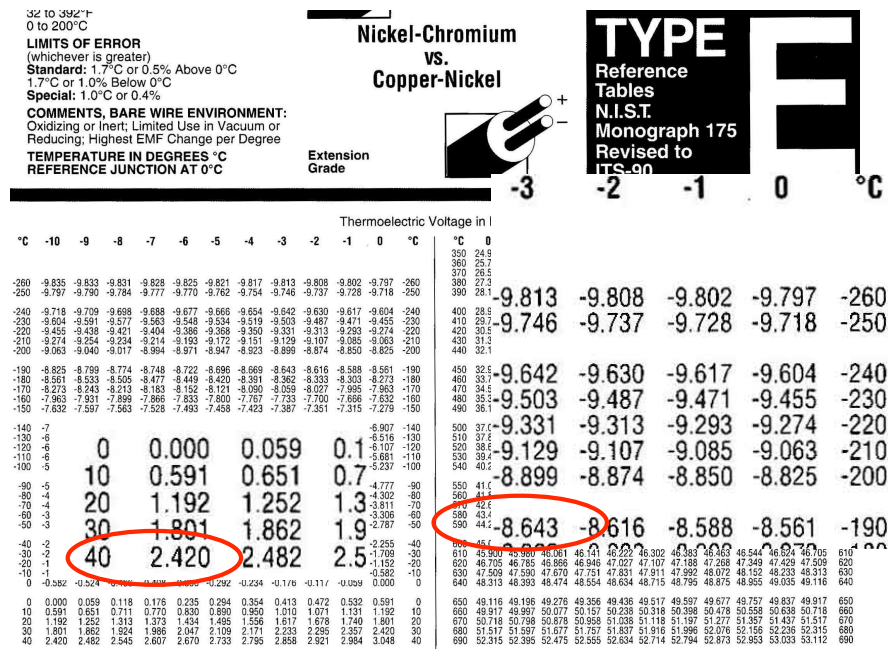


- A specific voltage is created to buck, or cancel, V_{ref} allowing $V(T)$ to be read directly
 - Advantage: faster than software compensation
 - Disadvantage: compensation voltage is specific to only one type of thermocouple wire at a time



Thermocouple - Example

- A type E thermocouple is used to measure $T = 80 \text{ K}$ with $T_{\text{ref}} = 40 \text{ }^\circ\text{C}$, (313 K)
 - What voltage is measured at the meter?
 - What is the reference voltage?
 - If the voltage resolution is 0.01 mV, what is the temperature resolution?



$$T = 80 \text{ K} = -193 \text{ }^\circ\text{C}$$

$$V_{\text{meas}} = V(T) - V_{\text{ref}} = -8.643 - 2.420 = -11.063 \text{ V}$$

$$V_{\text{ref}} = 2.420 \text{ V}$$

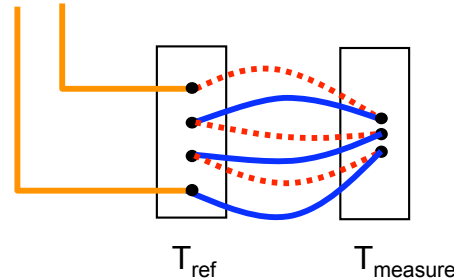
$$\text{@ } 80 \text{ K, } dV/dT = 26.8 \text{ V/K}$$

$$\text{With } dV = 10 \text{ } \mu\text{V} \quad dT = 0.37 \text{ K}$$



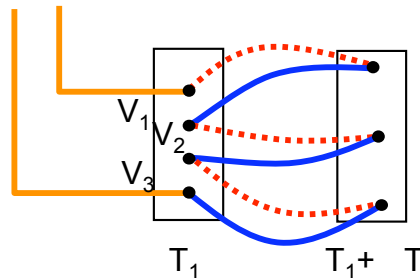
Thermopiles

- To increase signal:



- A series connection of 'n' pairs
 - produces n times the emf
 - Reduces temperature error by $\sim \frac{1}{\sqrt{n}}$

- To determine a spatially averaged temperature



$$V_1 = (T_1 + T) T_1$$

$$V_2 = (T_1 + T) T_1$$

$$V_3 = (T_1 + T) T_1$$

$$V_{total} = 3 T$$



Cryogenic Thermocouples

- Commonly used types for cryogenic temperatures:
 - Type E: Ni-Cr, Cu-Ni (constantan)
 - Highest α of types E, K, T (best down to 40 K)
 - Low thermal conductivity
 - Type K: Ni-Cr, Ni-Al
 - 8.5 $\mu\text{V/K}$ @ 20 K (vs. 4.1 $\mu\text{V/K}$ for type E)
 - Type T: Cu, Cu-Ni
 - Ag-Fe: high thermal power, but power decreases with time if stored at room temperature
- Important notes regarding use of thermocouples:
 - Voltage arises from region where $dT/dl \neq 0$
 - Joints must be made in regions where $dT/dl = 0$
 - If used in presence of magnetic fields, ensure that along the TC path, temperature is constant in regions of changing field, or field is constant in regions of changing temperature. ($\alpha = \alpha(H, T)$)
 - Minimize number of joints
 - Avoid dissimilar material joints at instrumentation feed-thru's
 - Heat sink TC wire before reaching the point of measurement



Thermometers - Considerations

- Temperature range
- Type of signal: voltage, capacitance
- Temperature sensitivity: change in signal per change in temperature
- Response time: size, thermal mass
- Mounting package
- Magnetic field sensitivity
- Strain sensitivity
- Repeatability (thermal cycling)
- Long term stability
- Radiation resistance
- Calibration
- Excitation requirement
- Cost



Thermometers - options

- Diodes (semiconductors): Si, Gas, GAIAs
 - Temperature dependent forward bias voltage
 - Small, fast response
 - Constant current source (10 A)
 - Very field dependent
 - Moderate sensitivity over large T-range
- PTC resistors (metal): Pt, Rh-Fe
 - Positive temperature coefficient
 - Very stable
 - Large size, slow response
 - Sensitive to magnetic fields
 - Fairly good sensitivity
 - Strain sensitive
- NTC resistors (semiconductors): CGR, GR, CR, RuO₂, Cernox™
 - Negative temperature coefficient
 - High sensitivity over limited temperature range (CGR, GR, CR)
 - Negligible field dependence (CGR, Cernox™, RuO₂), large field dependence (GR)
 - Strain sensitive encapsulated thermal sensing through the leads
 - Moderate response
- Capacitors
 - Insensitive to magnetic field
 - Sensing circuit requires care and attention



Resistance Thermometers

- Which thermometers would you choose for the following situations?
 - Winding of Tevatron magnet:
Cernox™, CGR, Rox™
 - Fluids experiment in helium II:
CGR, GR, Cernox™
 - Characterize performance of LH₂ liquefier:
GR, Pt, Rh-Fe, Cernox™
 - Cool-down study of an 80 K cryocooler:
Pt, TC, Si-diode, Cernox™



Thermometers

- Factors contributing to uncertainty:

- Sensor sensitivity:

$$S_T = \frac{\% \text{ change in signal}}{\% \text{ change in } T} \quad \text{dimensionless sensitivity}$$

- Voltmeter uncertainty

$$\frac{U_{T,V}}{T} = \frac{U_V/V}{S_T} = \% \text{ uncertainty in } V \cdot \frac{\% \text{ change in } T}{\% \text{ change in } V}$$

- Current source uncertainty

$$\frac{U_{T,I}}{T} = \frac{(U_I/I) R_d/R_s}{S_T}; \quad R_d = \frac{dV}{dI}, \quad R_s = \frac{V}{I}$$

- Calibration uncertainty – see mfc.

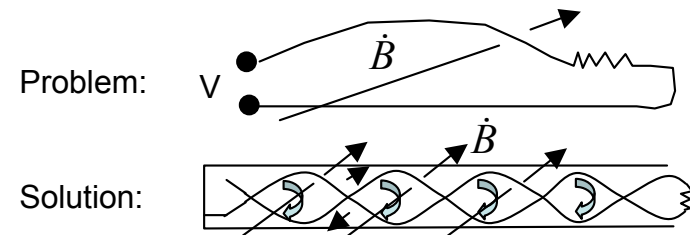
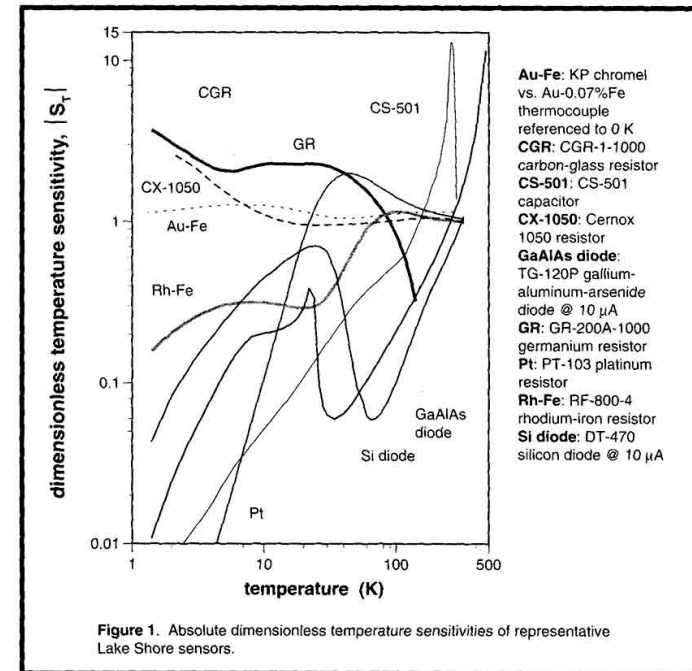
- Thermal noise – usually negligible

- Electromagnetic noise: $emf = \frac{dB}{dt} \cdot A$
 - Twisted pairs

- Shielding – connect shield at one end only – preferably at signal source

- Combined total uncertainty:

$$U_T = \left(U_{T,V} \right)^2 + \left(U_{T,I} \right)^2 + \left(U_{T,Cal} \right)^2 + \left(U_{T,therm_noise} \right)^2 \frac{1}{2}$$

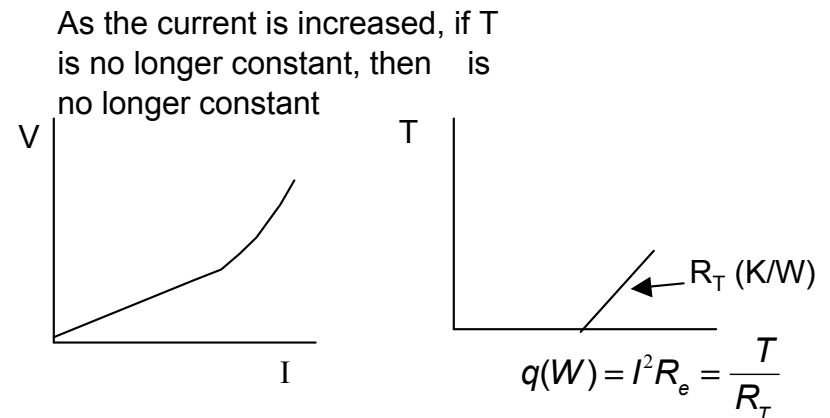
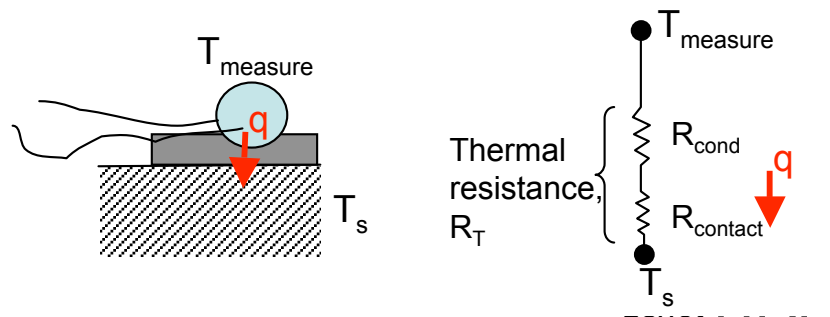


Thermometers

- Factors contributing to error (i.e. bias)

“A thermometer always indicates a temperature intermediate between that of the region being investigated and any other environment with which the thermometer has thermal communication.”

- Self heating



A compromise must be made between signal uncertainty and self-heating error

Low I: $U_{T,I} = T \frac{U_I/I}{S_T}$

The diagram for low current shows a small circular area with a central point x . A vertical double-headed arrow indicates a small temperature difference $U_{T,I}$ across the area.

High I: T_{SH}

The diagram for high current shows a larger circular area with a central point x . A vertical double-headed arrow indicates a larger temperature difference $U_{T,I}$. A larger vertical double-headed arrow labeled T_{SH} indicates the self-heating error.

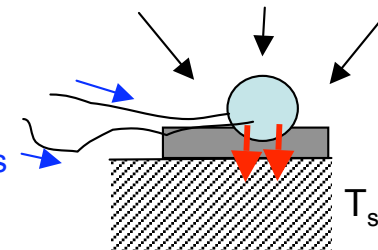


Thermometers: error factors (cont)

- Parasitic heat leak

Thermal radiation

Conduction along
Instrumentation leads



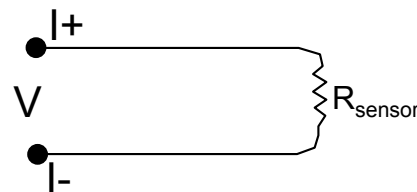
Example: 1 pair of 26 AWG (d=0.4 mm) copper wire, L = 1 m, T = 220 K

$$q_{cond} = \frac{A}{L} k(T) dT = 2 \frac{(4 \times 10^{-4})^2}{4} 92 \times 10^3 = 23 \text{ mW}$$

T = 23 mK, when $R_T \sim 10 \text{ K/W}$

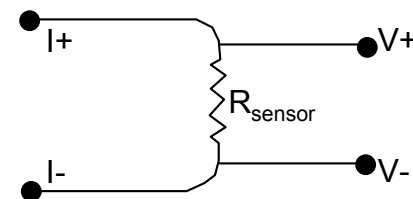
- Lead resistance

Problem:



$$V = I(R_{sensor} + R_{leads})$$

Solution: 4-wire connection



Thermometers: error factors (cont)

- Thermal emf

Problem: the Seebeck coefficient of different materials, in regions of T produces a thermal emf, even when no current is flowing

Solution: reversing polarity, or multiple current levels

$$V = (V_1 + V_{emf}) - (V_1 + V_{emf}) / 2 \quad (\text{reverse polarity})$$

$$V = (I_1 R + V_{emf}) - (I_2 R + V_{emf}) \quad (\text{known values of } I)$$

$$R = \frac{V}{(I_1 - I_2)}$$



Thermometers: Do's & Don'ts

- Thermally anchor leads as close to measurement temperature as possible (5 -10 cm length)
- Use twisted, shielded leads to minimize electromagnetic noise (connect shield at one end only)
- Minimize conduction heat load by using long lengths, small diameters, low thermal conductivity materials
- Follow recommended excitation levels to avoid self heating
- Isolate low-level signal leads from high-level signal leads
- Reverse polarity to cancel thermal emf components

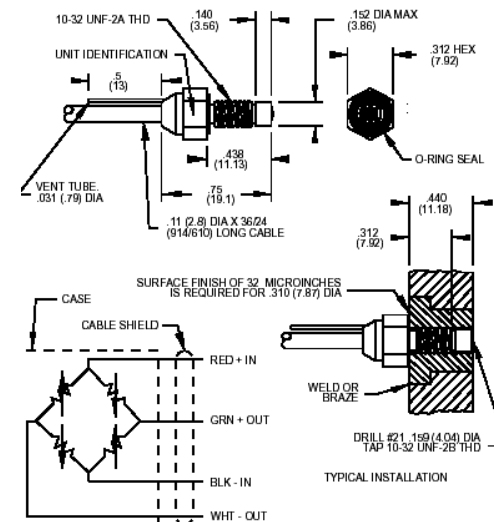


Pressure

- Piezoresistive transducers
 - Resistance bridge – 4 active arm strain-gauge
 - Calibration required at temperature
 - Example: Endevco 8510B
 - Typical price: ~ \$1K per each
- Pressure capillary extension
 - Extend capillary from cold environment up through cryostat to room temperature environment
 - Ensure leak-tight
 - Check mean free path length for low pressure (vacuum) applications



Actual size

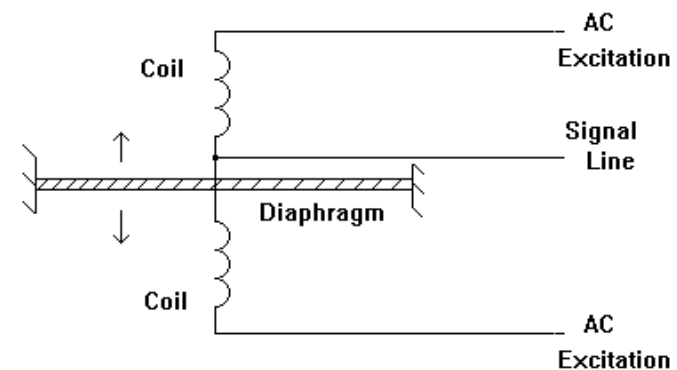


STANDARD TOLERANCE
INCHES (MILLIMETERS)
XX = +/- .05 (XX = +/- .8)
XXX = +/- .010 (XXX = +/- .25)



Pressure

- Variable reluctance transducers
 - Magnetically permeable stainless steel diaphragm clamped between inductive pick-up coils
 - Diaphragm displacement changes induction of both coils
 - AC bridge / amplifier circuit converts inductive change to proportional DC output voltage



Variable Reluctance Circuit



Cryogenic flow metering techniques

Single phase flows

1. Pressure drop devices based on Bernoulli Principle
 - a) Venturi
 - b) Orifice plate
 - c) Pitot tube
- $$p = \frac{1}{2} v^2$$
2. Friction pressure drop (laminar flow elements)
 3. Hot wire anemometers based on $h = f(v)$
 4. Acoustic flow meters based on Doppler effect
 5. Turbine flow meters where frequency \sim velocity
 6. Optical techniques (Laser Doppler)

Two phase flows

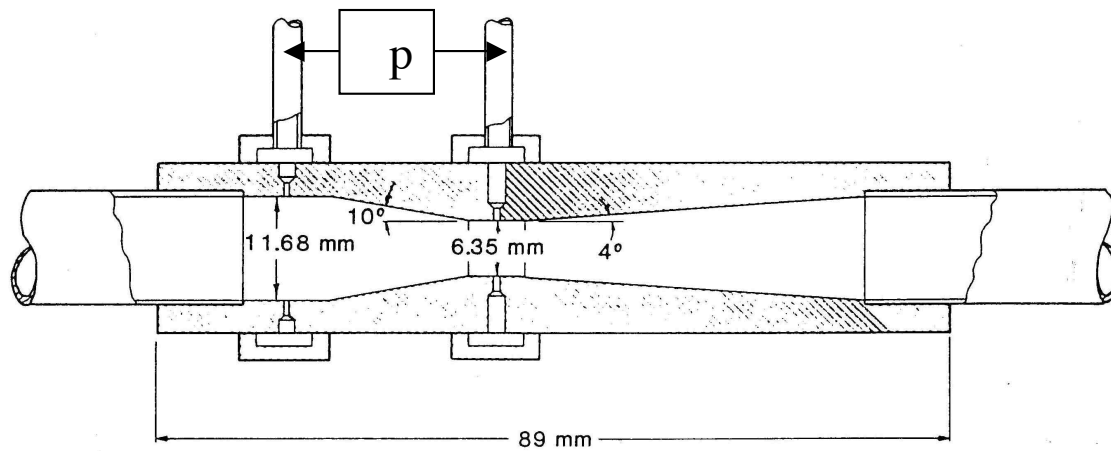
1. Void fraction measurement (A_v/A)
 - a) Capacitance measurement
 - b) Optical absorption
2. Quality measurement (m_v/m)

These techniques are for the most part all used in classical fluid flows.

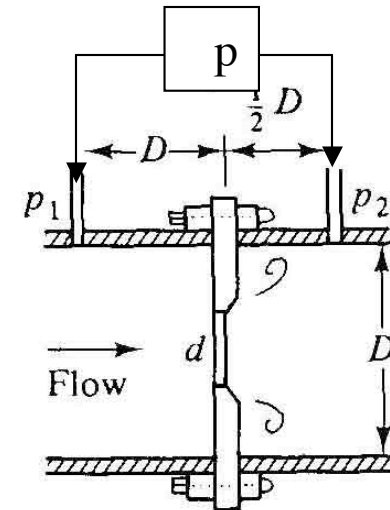
The unique "cryogenic" features have to do with instrumentation used to detect signal and need for low heat leak.



Pressure drop devices



Venturi



Orifice

- Venturi flow meters have advantage over orifice plate due to low loss coefficient

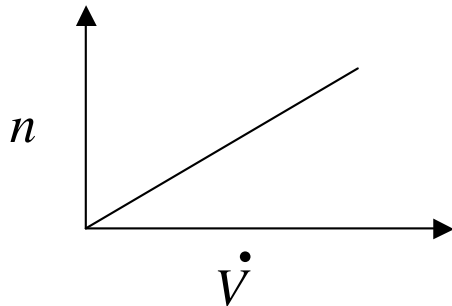
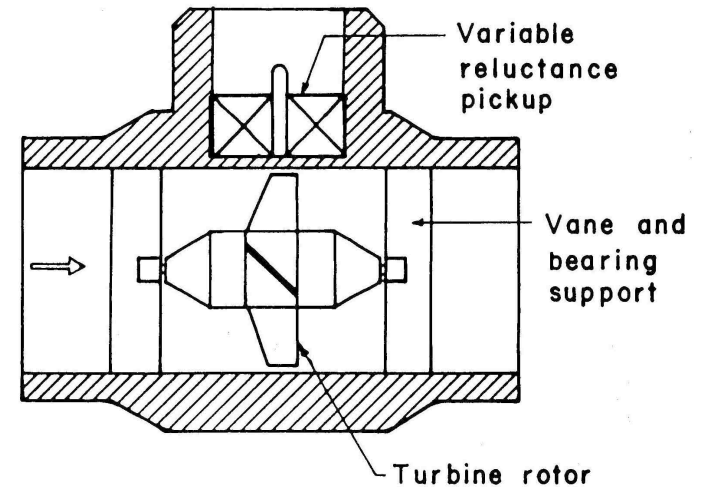
$$\dot{V} = A_t v_t = C_d A_t \frac{2 p / \rho}{1 - \beta^4}^{1/2} \quad \text{where } \beta = D_t / D$$

- C_d is the discharge coefficient (~ 1 for venturi & 0.6 for orifice)
- Pressure transducer should be located at low temperature, if possible
- Require determination of density at meter inlet



Turbine flow meters

- Rotation speed is proportional to volumetric flow rate
- Linear response function allows a wide range of operation

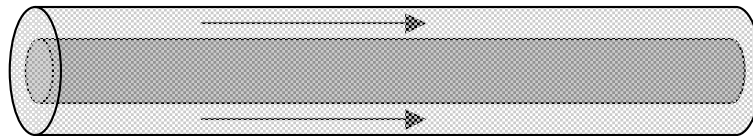


$$\dot{V} = \frac{D_b A_f}{\tan b} n = Kn$$



Two phase flow measurement

- Measurement of flow quality (m_v/m) in a two phase mixture (liquid + vapor) is difficult.
 - Vapor velocity and liquid velocity may be different
 - Flow regime is not known
- Measurement of void fraction (A_v/A) is more straightforward
 - Capacitive meter based on different dielectric constant



Co-axial capacitor

- Optical techniques
- Total mass flow rate can be determined in some part of the circuit where the fluid is single phase using a conventional flow meter



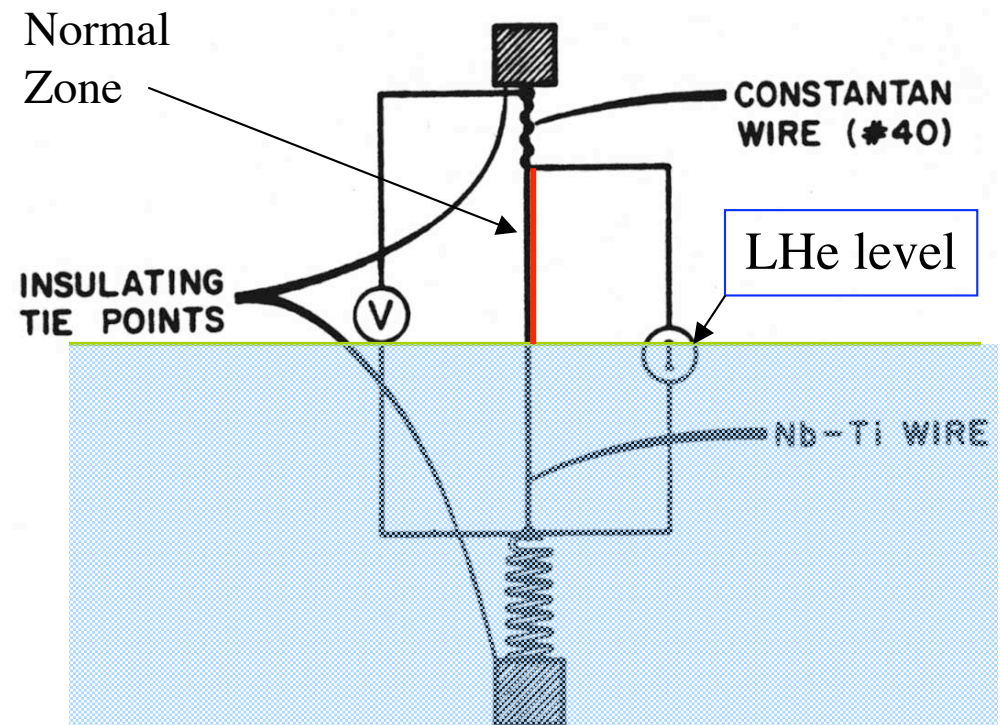
Liquid level measurement techniques

- Continuous level measurement
 - Superconducting wire level device
 - Capacitive level measuring systems
 - Transmission line system
 - Ultrasonic level measurement
 - Hydrostatic (head) level measurement
- Discrete level measurement
 - Liquid-vapor detectors (resistive, superconducting)
 - Acoustic “Dip stick” method
- Mass measurement (gauging)

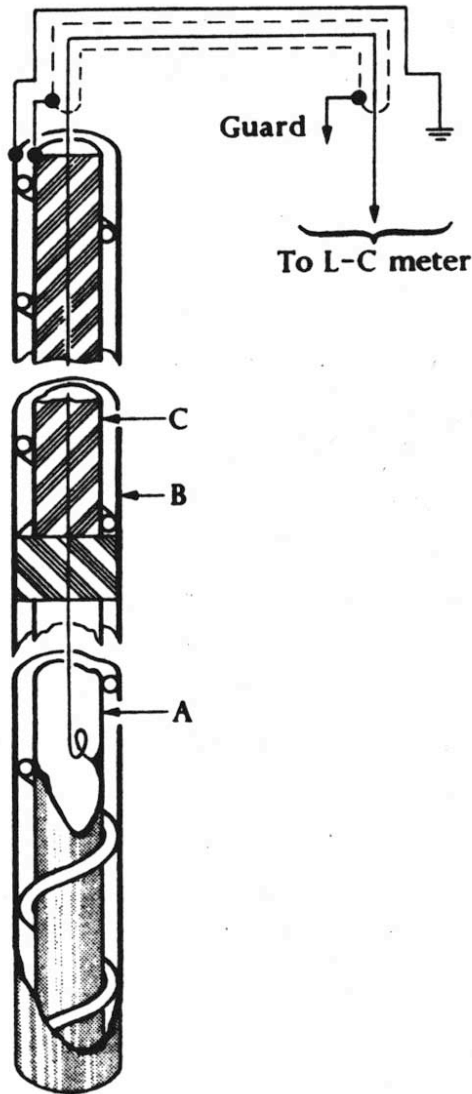


Superconducting wire level meters

- Developed by Efferson (1970), but now a commercial product
- Heater drives the normal zone of SC wire to the liquid interface, where it stops due to improved heat transfer
- Units are most often calibrated in LHe at 4.2 K
- Variable performance in He II due to improved heat transfer
- Some SC level meters based on HTS materials have been developed for LN₂



Capacitive Level Gauges



Most are custom, some are available as a prototype commercial units, particularly for high dielectric constant fluids (e.g. LN₂)

Measurement Methods:

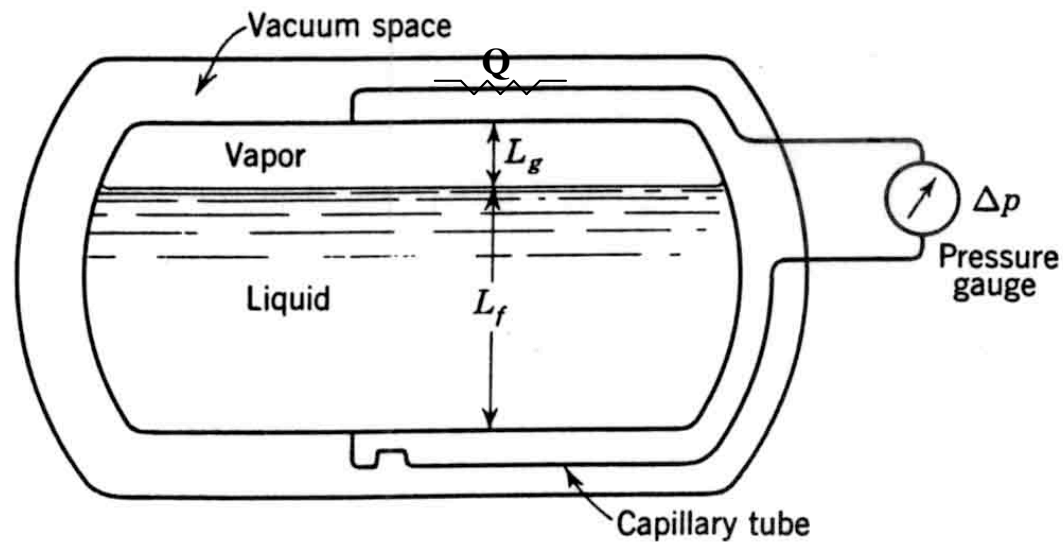
- AC Bridge
- High frequency oscillator
- Time constant method
- Phase-lock loop technique

In-situ calibration necessary

$$\text{Sensitivity} = \frac{dC}{dH_f} = \frac{2 \epsilon_0 \left(\frac{f}{g} \right)}{\ln(D_0 / D_i)}$$



Differential pressure (head) gauge



Requirements

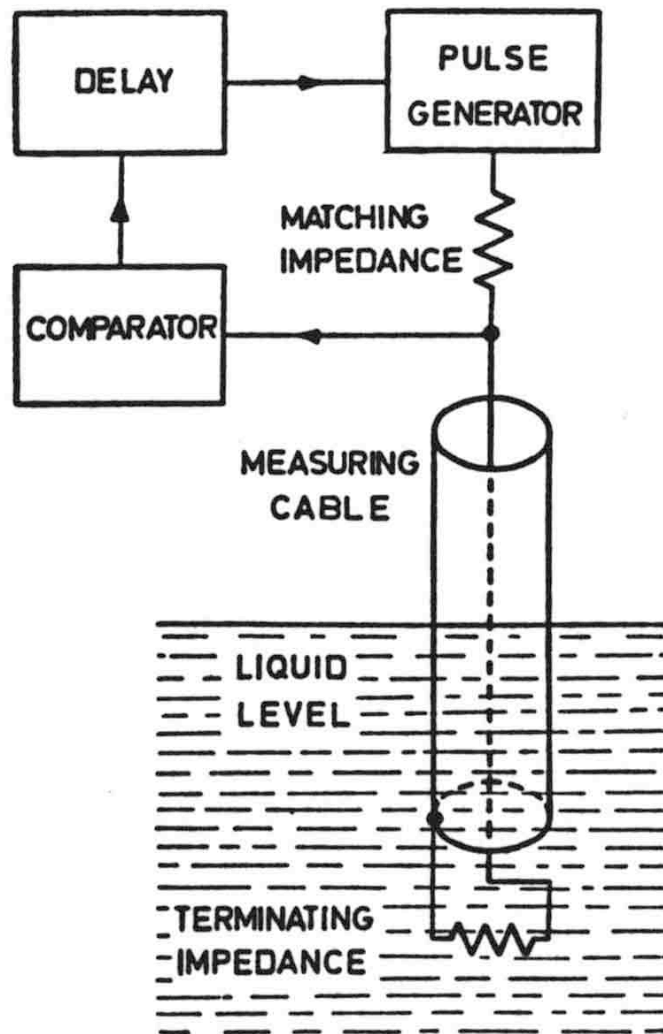
- Pressure gauge must be located in cryostat
- $dp/dL = \Delta g$
= 1.42 (Pa/mm)_{helium}
- Heat load may be large to keep vapor line dry

$$L_{liquid} = \frac{p}{g} \frac{L_{total}}{g}$$

	He	H ₂	Ne	N ₂	O ₂	Ar
l	125	70.8	1240	861	1141	1394
g	16.7	1.33	9.4	4.6	4.47	5.77



Transmission level technique



- Original system developed by Lindstrom, et al, Rev Sci Inst. (1970)
- Based on reflected signal in a coaxial line partially filled with liquid

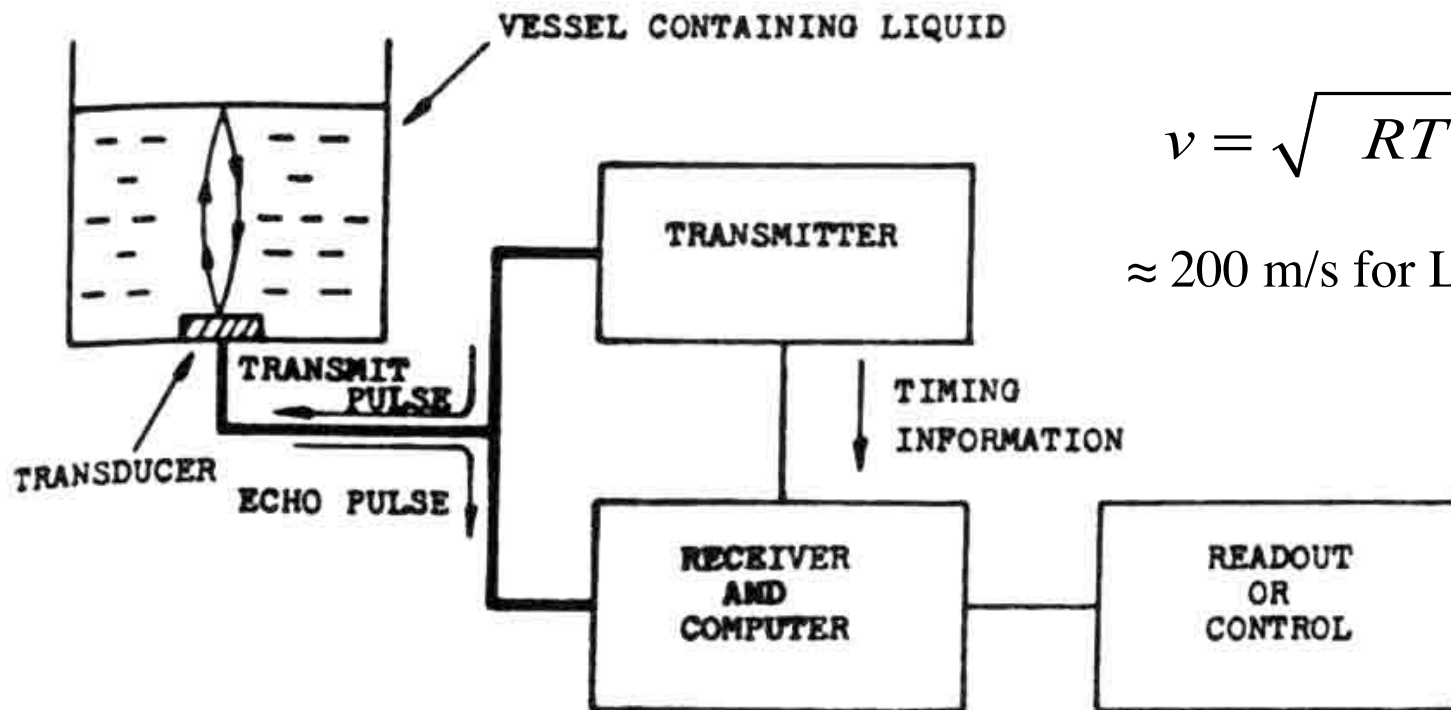
$$Z_f = Z_g \sqrt{\frac{g}{f}}$$

- Probe design is easier than capacitor
- Small heat deposition and fast response makes device attractive



Ultrasonic level measurement

Signal travels at sound speed



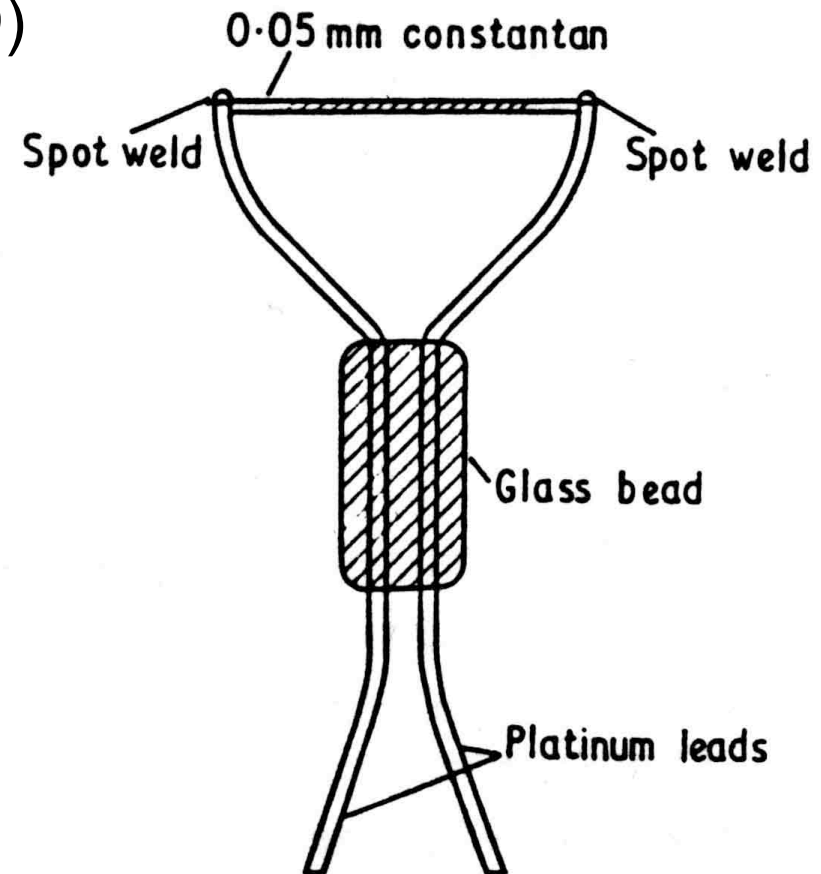
$$v = \sqrt{RT}$$

≈ 200 m/s for LHe

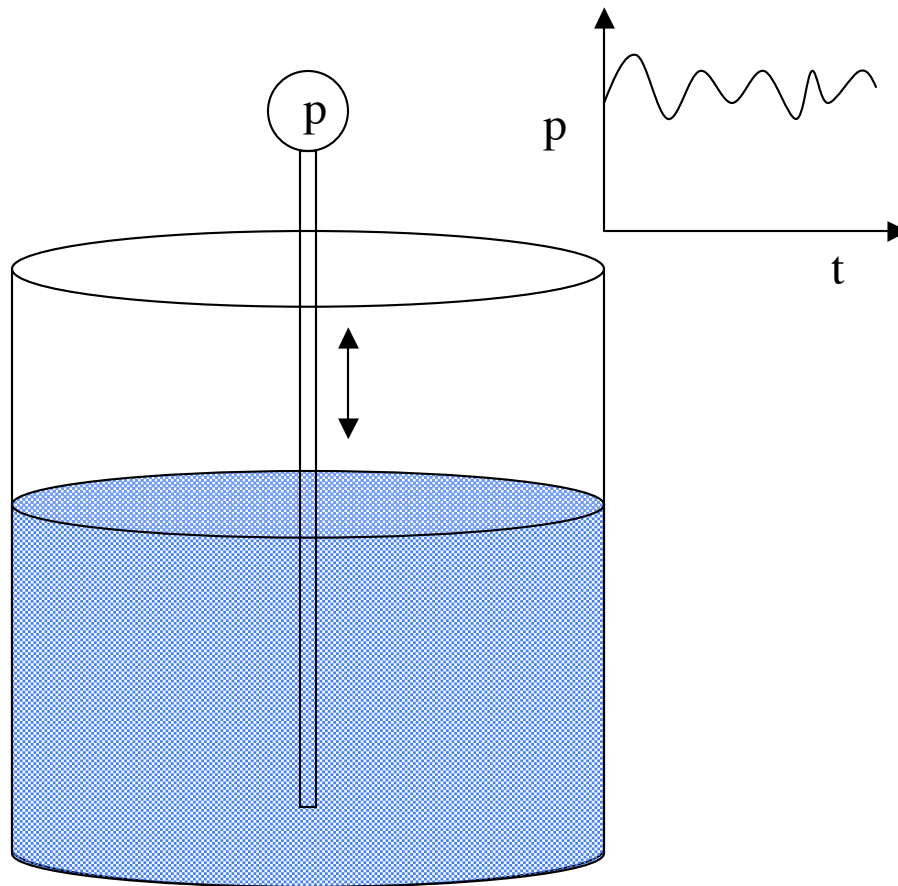


Discrete level measurement techniques

- Liquid vapor detection (LVD)
- Types of devices:
 - Superconducting thin films (SnAu)
 - Hot wire or film
 - Semiconductors
- Operating current must be sufficient to self heat the sensor in vapor, but not in liquid
- Sensor must be small to minimize heat generation in liquid



“Dip Stick” level measurement

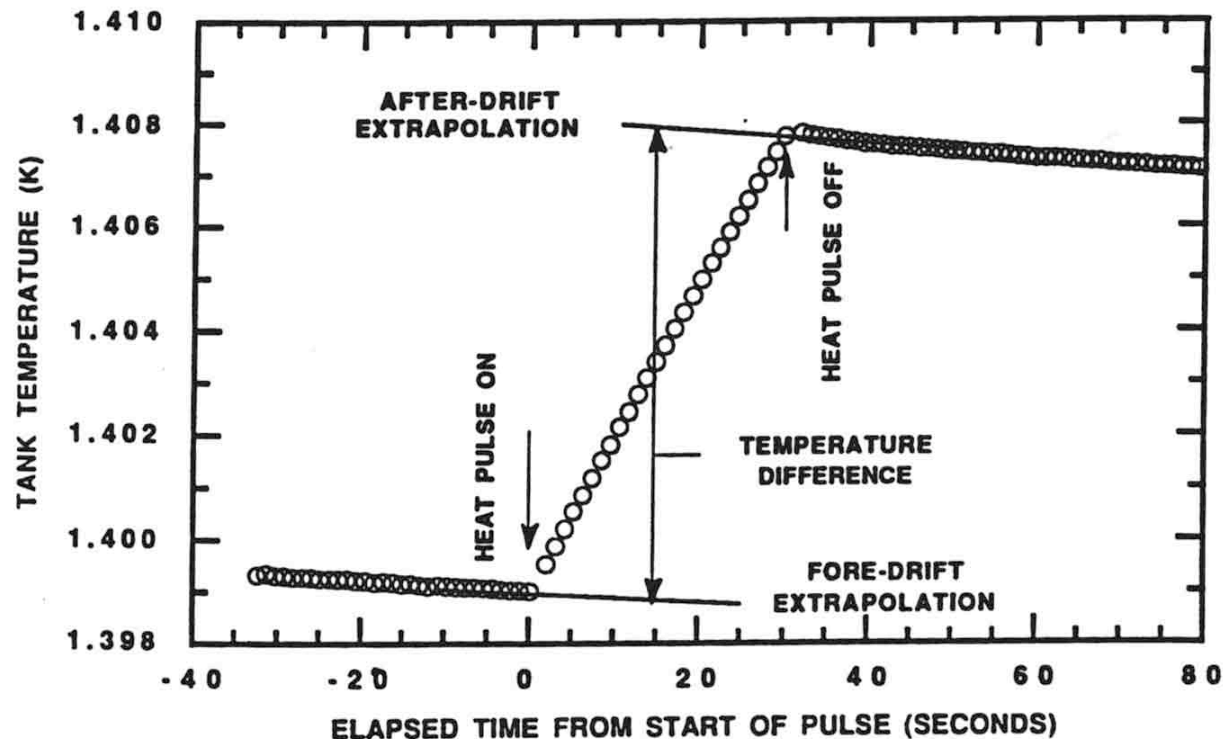


Acoustic oscillation
changes frequency &
amplitude when capillary
leaves liquid



Heat Pulse Mass Gauging

- Measurement of He II volume (mass) by heat pulse technique
→ mass = Q / h
- Technique used extensively for space based He II cryostats but also pressurized He II systems for superconducting magnets



From Volz, et al
Advances in Cryo. Engn.
Vol 35 (1990)



Summary of Level Measurement Techniques

		Availability	Readout	Range of heat Deposition
Continuous Level Measurement				
	Capacitive gauge	Prototype	Frequency	Less than 1mW
	Superconducting wire	Commercial	Voltage	Tens of mW's
	Transmission line	Development	Frequency	On the order of W
	Heat transfer based	Development	Power/temperature	Tens of mW's
	Floats	Development	Visual/voltage	Negligible
	Hydrostatic	Development	Pressure	On the order of mW's
	Ultrasonic	Development	Frequency	Less than 1 W
Liquid-Vapor Detectors				
	SC wire	Development	Voltage	On the order of mW's
	Resistive	Development	Voltage	On the order of mW's
	Ultrasonic	Development	Frequency	Less than 1 W
	Optical	Development	Light intensity	Less than 1 W
Mass gauging				
	Internal energy change	Development	Temperature	On the order of 1 Joule

